EEMF 5283 Plasma Technology Laboratory (2 semester credit hours) Laboratory will provide a hands-on experience to accompany EEMF 5383. Topics to include: Vacuum technology [pumps, gauges, gas feed], plasma uses [etch, deposition, lighting and plasma thrusters] and introductory diagnostics. Recommended Corequisite: EEMF 7171. Corequisite: EEMF 5383. (0-2) R (2016-02-06 00:08:09)